

WHAT IS CLAIMED IS:

1. A substrate treatment apparatus comprising:
 a carrier which accommodates a substrate therein;
 a treatment chamber configured to polish or clean a
substrate therein; and
 a control device configured to continuously execute a
plurality of jobs concerning a test conveyance of the
substrate in the treatment chamber, wherein
 the control device continuously executes the
plurality of jobs not through an unloading treatment of moving
the carrier away from the treatment chamber, and not through a
loading treatment of approaching the carrier to the treatment
chamber, between the plurality of jobs.
2. The substrate treatment apparatus according to claim
1, wherein
 the control device continuously executes the
plurality of jobs in order of registration or at random.
3. The substrate treatment apparatus according to claim
1 or 2, wherein
 the carrier can accommodate a plurality of substrates
therein, and
 the control device executes the plurality of jobs to
a substrate which has been assigned by the plurality of jobs,
out of a plurality of substrates that have been accommodated
in the carrier.

4. The substrate treatment apparatus according to any one of claims 1 to 3, wherein

the control device determines whether the carrier is subjected to the loading treatment or not, before the first job out of the plurality of jobs is executed, and when the carrier is not subjected to the loading treatment, subjects the carrier to the loading treatment and executes the first job.

5. The substrate treatment apparatus according to any one of claims 1 to 4, wherein

the substrate treatment apparatus can set the number of the substrates to be conveyed or the finish time, as a termination condition for continuous execution of the plurality of jobs, and

the control device determines whether the termination condition is satisfied or not while the plurality of jobs are continuously executed, and when the termination condition has been satisfied, subjects the carrier to the unloading treatment and finishes the substrate test.

6. The substrate treatment apparatus according to any one of claims 1 to 5, wherein

the plurality of carriers are provided, and

the control device executes the plurality of jobs simultaneously to the substrates which are accommodated in each of the plurality of carriers.